

# HPT History



- History: HPT has been a provider for over 30 years of technical and commercial solutions to the semiconductor and other high-tech industries
- Group: Part of the CMAT Group (Consorzio Meridionale Alta Tecnologia), it enjoys relationship with other group companies that can provide engineering and R&D support as needed.
- Location: Based in the Greater Milan area it employes 15 people, to serve the European market.
- Verticals: Main verticals served include the Semiconductor Industry, Industrial Gas Manufacturers, Green/Renewable energy providers, battery manufacturers
- Products: Offering ranges from UHP gas distribution components like valves, fettings etc, to gas analyzers and analytical systems, gas detectors, Toxic gas abatement systems, and FM approved corrosive fumes ducts



# **Our Company Culture**



Acting as the lifeblood of business, we aim to be the engine of progress for innovative companies



# **Mission**

We manage complex systems with speed and scale, growing everyday in the global fast-pace manufacturing industry



# **Values**

- People Health and Safety
- Excellence and Reliability
- Flexibility + Speed = Agility
- High-end Creativity
- Integrity
- Winning together



# Industry Partners



#### **STMicroelectronics**

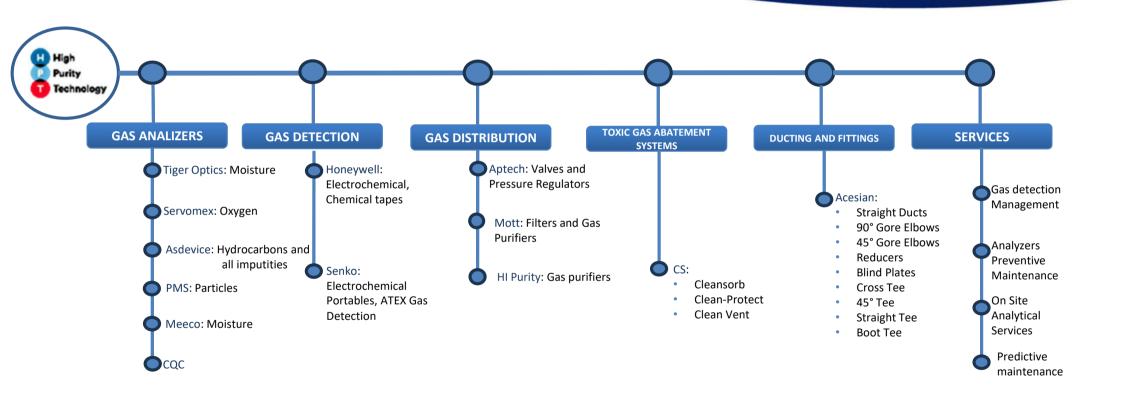
- Enel
- Infineon
- Lfoundry
- Fincimec
- CNR
- Exyte
- Air Liquide
- Texas Instrument
- Micron

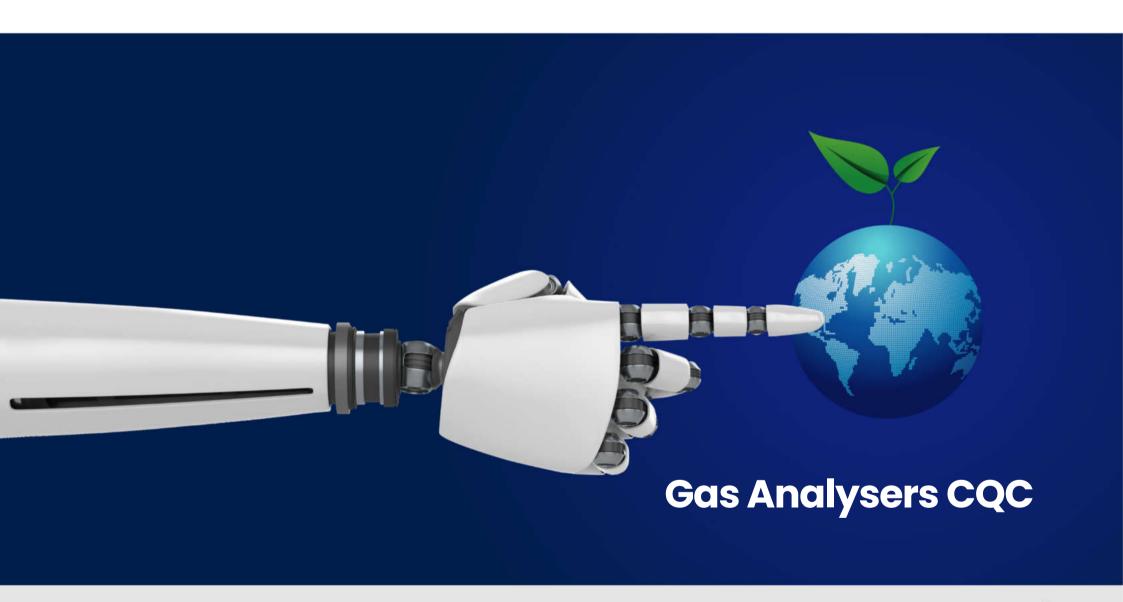
- Applied Materials
- Technoprobe
- Sapio
- Linde
- Vishay
- Indexa





# Our Portfolio and Value Proposition



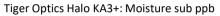




# Gas Analyzers and CQC

- Stand Alone
- In an analytical rack (CQC)
- Moisture, Oxygen, Hydrocarbon analyzers
- Continuous gas analyzers (CGA)
- Gas Chromatographs
- Particle counters
- Quality control at the inlet-outlet of Gas Purifiers







Servomex: ppm-ppb Oxygen Analyzer



Meeco: Moisture ppm-low ppb



AS Devices: Hydrocarbon Analyzer

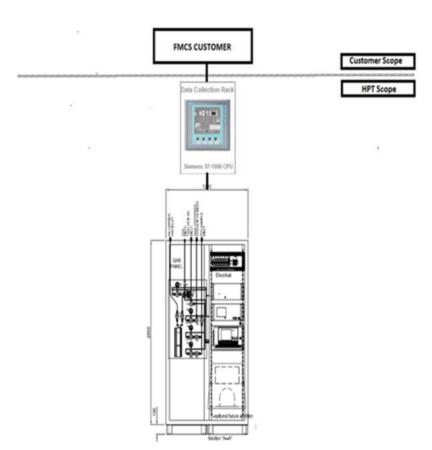


**PMS: Particles Counters** 

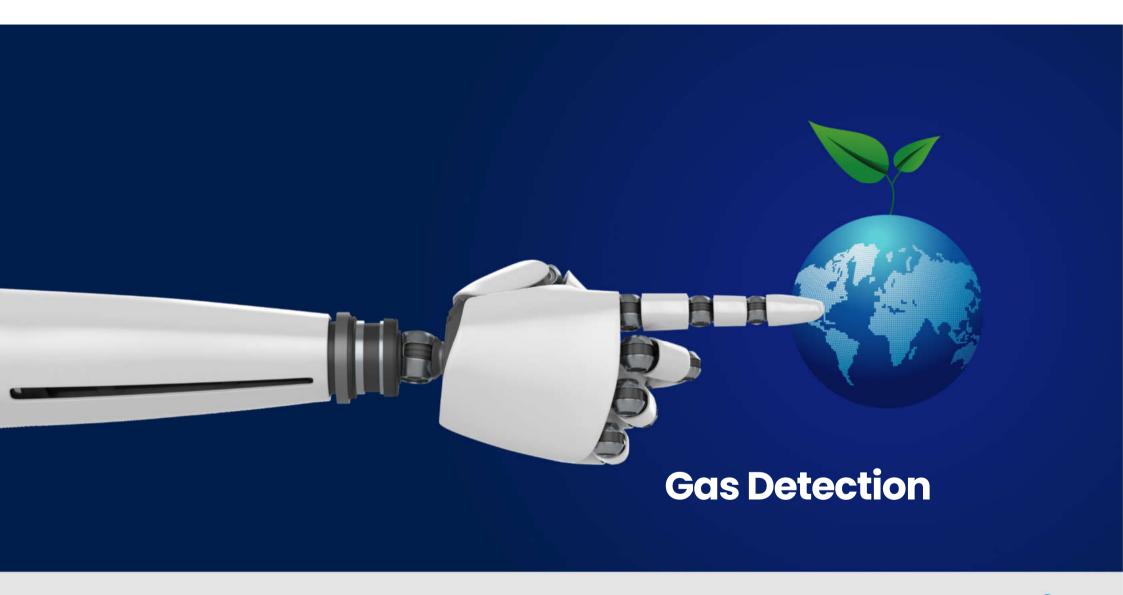


### cqc

- Independent system integrator. Choice of the best analyzers for the application
- Class 100 clean room assembly, orbital welding, minimization of dead volumes.
- Selection of state-of-the-art components for all wetted surfaces
  - 316 SSL <10 micrometer
- Construction according to SEMI Standard F-20.
- Scada and connection to Customer FMCS
- FMCS installation, maintenance and support at all ST Micro sites by fully trained personnel









### Gas Detection

- Fixed and Portable gas detection
- Electrochemical, Chemical tape and FTIR technologies
- Complete TGMS (Toxic Gas Monitoring Systems)



Honeywell Electrochemical



Senko Electrochemical



Honeywell: Chemical tapes



Senko: atex fixed diffusion

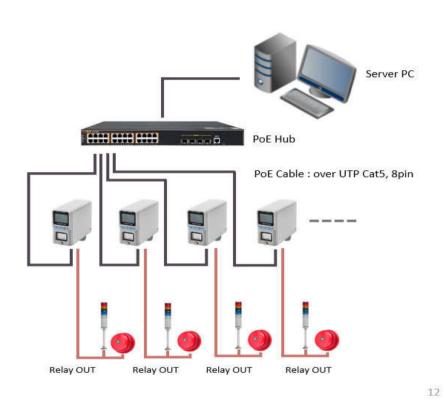


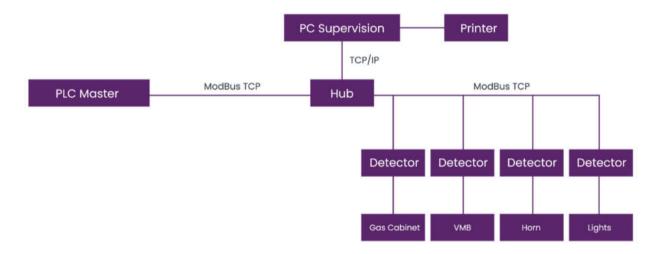
Senko: portable multi/mono gas



#### Totally open architecture

# Gas DetectionTGMS





No 'proprietary' software needed to change points. PoE







# UHP GasDistributionSystems

- Pressure Regulators
- Valves
- Piping and fittings
- POU and bulk UHP gas filters
- Gas Purifiers



Ap-Tech Pressure regulators & Valves



Mott: UHP Gas filter



Mott: Gas Purifiers



## APTECH MANUAL AND PNEUMATIC VALVES:

- Replaceable seat
- Stainless steel 316L VAR secondary remelt or Ni-Cr-Mo alloy construction
- Operating pressures from 125 psig (9 bar) to 3,000 psig (207 bar)
- Flow capacity 0.23 to 0.29 Cv
- · Multi-port options available





# Valves Pressure regulators and Piping

#### APTECH PRESSURE REGULATOR:

- · Single stage
- SS 316L VAR secondary remelt or super alloy construction
- Cleaned, assembled and packaged for high purity semiconductor applications
- Vacuum to 3,500 psig (241 bar) inlet HR option to 4,500 psig (310 bar)
- Flow rates—standard to 30 slpm (1 scfm)





#### MICRO BULK GAS PURIFIERS:

Offer moderate flow rates, serving high purity and permanently installed gas delivery systems.

These solutions are designed to meet the specific requirements of any gas delivery system by allowing for customization of critical features.

#### Applications:

- High production rate weld gas/purge gas
- Glove box purge gas
- Annealing cover gas
- UHP Applications
- · Additive manufactoring



#### **GAS FILTERS:**

UHP Gas Filters provide 9-log fltration of particle down to 0.0015µm resulting in particle-free gas.

These filters are compatible with most high purity electronics grade process gasses.



### Filters and Purifiers

#### FIBER BULK FILTERS:

Provide filtration of particles down to 0.0015µm resulting in particle-free gas. In additional, the flow versus differential pressure performance of these filters is equal or superior to the performance of the competitive polymer products.

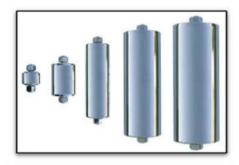
Metal filter is used downstream of purification sistems, cryogenic systems and air separation plants to ensure gas quality and provide protection against castastrophic particle disturbance.





#### **HI PURITY-GAS PURIFIERS**

#### GAS PURIFIERS







#### **IGP Purifier series**

- Purification method: Physical (Molecular Sieve) + Chemical Adsorption (Ni cat.)
- Sample gas: N2, Ar, He, H2, O2, CO2, CDA, Kr, Ne, Xe, NH3
- impurity: H2O, H2, CO2, O2, CO, NMHC, Bases, Organics, Acids, Refractory Compounds, Metals
- Flow rate (Max.) : 5~2000 slpm

#### **R/N/HGGP Purifier series**

- Purification method : Chemical Adsorption (Getter)
- · Sample gas : N2, Ar, He, H2
- impurity : H2O, H2, CO2, O2, CO, CH4, N2
- Flow rate(Max.): 1~5 slpm
- · Flow rate option: 50/100/150 slpm

#### **GP Purifier series**

- Purification method: Physical (Molecular Sieve) + Catalyst (PdO) or Chemical Adsorption (Ni Cat, Getter)
- Sample gas: N2, Ar, He, H2, O2, CO2, CDA, Kr, Ne, Xe, NH3
- impurity: H2O, H2, CO2, O2, CO, CH4, Bases, Organics, Acids, Refractory Compounds
- Flow rate(Max.): Getter type(up to 300 Nm³/hr)

From point of use in line ambient gas purifiers to large bulk gases catalytic and getter purifiers



# Purifiers line up

#### **IGP SERIES** In-Line Purifier (ambient)

Process Gas	Model				Impurities Removed				— Lifetime	Flowrates
Process Gas	iviouei	O <sub>2</sub>	H₂O	со	CO <sub>2</sub>	H <sub>2</sub>	CH₄	N <sub>2</sub>	Lifetifie	riowiates
Rare Gas	IGP-R	<1 ppb	<1 ppb	<1 ppb	<1 ppb	ব্যু চুকুট			Liosbard Libritron	Cop to 20,000 signs
Nitrogen	IGP-N	<1 ppb	<1 ppb	<1 ppb	<1 ppb	47.38p			Livided Library	Up to 20,000 dem
Hydrogen	IGP-H	<1 ppb	<1 ppb	<1 ppb	<1 ppb				Linesand Linkshina	Up to 25,000 sipen

#### **GASPURI SERIES** Heated Getter Purifier

Process Gas	Model	Purification Process		Lifetime	Flowrates						
Flucess Gas	Model	rumcation rrocess	O <sub>2</sub>	H₂O	со	CO <sub>2</sub>	H <sub>2</sub>	CH <sub>4</sub>	N <sub>2</sub>		Tiowrates
Rare Gas	GP-G Series	Getter	<1 ppb	<1 ppb	<1 ppb	<1 ppb	<1 ppb	<1 ppb	<1 ppb	Limited Lifetime	Up to 150 slpm
Nitrogen	GP-G Series	Getter	<1 ppb	<1 ppb	<1 pp'-	<1 pg 1	<1 ppb	<1 ppb		Limited Lifetime	Up to 150 slpm
Hydrogen	GP-G Series	Getter	<1 ppb	<1 ppb	<1 ppb	<1 ppb			<1 ppb	Limited Lifetime	Up to 100 slpm

#### **GP SERIES** Bulk Gas Purifier (Getter and catalytic)

		Pι	urification Proc	ess					lm	purities Remov	red						
Process Gas	Model	Absorber	Getter	Catalyst	H <sub>2</sub> O	со	CO <sub>2</sub>	O <sub>2</sub>	H <sub>2</sub>	CH <sub>4</sub>	N <sub>2</sub>	Acids	Base	Organics	Refractory Compound	Lifetime	Flowrates
Rare Gas	GP-G Series				<1 ppb	<1 ppb	<1 ppb	<1 ppb	<1 ppb	<1 ppb	<1 ppb					Limited Literana	Up to 3000 builder
Oxygen	GP-CA Series				<1 ppb	<1 ppb	<1 ppb		<1 ppb	<1 ppb						Auto-Regreserable	Up to 8000 metho
Hydrogen	GP-AG Series		~		<1 ppb	<1 ppb	<1 ppb	<1 ppb		<1 ppb	<1 ppb					Getter has a Limited Lifetime	Uy to 1000 lariou
Hydrogen	GP-A Series	~		~	<1 ppb	<1 ppb	<1 ppb	<1 ppb								Acto-Bayenessible	15g to 300Mee/flar
Hydrogen	GP-G Series	~	~		<1 ppb	<1 ppb	<1 ppb	<1 ppb		<1 ppb	<1 ppb					Lindad Lifetine	Up to Militalilie
Nitrogen	GP-A Series	~			<1 ppb	<1 ppb	<1 ppb	<1 ppb	<1 ppb							Asta-Negrourik	Up to 20,000Nm³/hr
Nitrogen	GP-CA Series		~		<1 ppb	<1 ppb	<1 ppb	<1 ppb	<1 ppb	<1 ppb						Auto-Bagessoniche	Up to 3,000Nm <sup>3</sup> /br
CDA	GP-A Series	~			<1 ppb							<5 ppt	<5 ppt	<5 ppt	<5 ppt	And Sequentials	15g to SSEMeether
CO2	GP-A Series	~		~	<1 ppb							<5 ppt	<5 ppt	<5 ppt	<5 ppt	Astr-Engenerals	Up in Philippelite



### ●In-Line Gas Purifiers



### In-Line Purifier IGP Series

#### **Product Highlights**

Serves UHP quality purification with simple connection

Low ppb level purification(Optionally ppt)

Quality: SUS316L Body, All leak checked, fully tested with APIMS Analyzer

Long lifetime by Factory Regenerable, Certified by APIMS analysis (Except some media)



Model	Maximism Flow (Mpm)	Average Flow (Non)	Maximum Pressure level	Connection Type	Diameter (inches (mm))	Face to Face (mites (med)	Face to Face with valves (motes (mm))
IGP1L	1	0.5	1000	1/4" VCR	1.5 [38.1]	3.3 [84.1]	8.91 [226.3]
IGPSI.	5	1.5	1000	1/4" VCR	1.5 [38.1]	5.1 [127]	10.60 (269.2)
KSP20L	20	5	250	1/4" VCR	2.0 [50.8]	6.3 [160]	11.90 [302.3]
KGP50L	50	9	250	1/4" VCR	3.0 [76.2]	8.2 [208.3]	13.80 [350.5]
KGP75I	75	10	250	1/4" VCR	3.0 [76.2]	7.9 [201.7]	13.54 [343.9]
KSP100L	100	12	250	1/4° VCB.	2.0 [50.8]	12.5 [317.5]	18.10 [459.7]
KGP120L	120	25	250	1/4° VCR	3.0 [76.2]	10.0 [254]	15.6 [396.2]
KSP250L	250	40	250	1/2" VCR	3.0 [76.2]	18.2 [462.3]	28.84 [732.5]
KSP300L	300	80	250	1/4° VCR	4.0 [101.6]	17.3 [439]	23.2 [589]
KGP500L	500	80	250	1/2" VCR	4.0 [101.6]	20.0 [508]	30.64 [778.3]
KSP1000L	1000	300	250	1/2° VCR	6.0 [152.4]	39.3 [999.7]	50.0 [1270.0]
KGP20001	2000	1000	250	MC VCR	6.0 [152:4]	50.8 [1290]	67.1 [1705]

The IGP -Extension purifies UHP Quality gas at ambient temperature without power sonsumption.

IGP-Extension does not require the additional power and heating as it purifies gas at room temperature.

2 Different media follow customer's application, and additional column is available if increased flowrate is expected.

Factory regeneration is also available, and Regeneration kit can be purchased (In this case, please contact to Hipurity Sales Dept).

#### **Optionally Available**

- MFM
- Pressure Transducer
- · Temperature Interlock
- 0.003um Particle Filter

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IGP Performance										
	Impurities Removed Engage Chily	Standard Unit	Outlet Performance							
N <sub>p</sub> Bare Gases	H <sub>2</sub> O	H <sub>1</sub> O, CO, CO <sub>p</sub> H <sub>p</sub> O <sub>2</sub>	<1 ppb							
14,	H <sub>2</sub> O	H2O, CO, CO, O;	< 1 ppb							
CDA, O <sub>2</sub>	11,0	N/A	< 1 ppb							

3GF Performance — Single Column (SC)									
Model	Impurities Removed	Adjustment Flow	Maximum Fressure Drop (seri	-	Witthout	Elements some)	Writight pu		
IGP200 G* SC M	11,0	200	1	196	21	66	< 400		
IGP1000-G1-SC-M	H <sub>i</sub> O	1000	,	196	188	114	< 400		
IGP3000-G1-SC-M	11,0	3000	4	234	127	102	< 700		
IGP5000 G* SC M	11,0	.5000	1	32%	155	186	< 2000		
IGP200-G*SC-AWI	H <sub>2</sub> O, CO, CO <sub>3</sub> , H <sub>3</sub> , O <sub>3</sub>	200	- 1	\$ 10ms	71	66	< 400		
IGP1000-G*SC-MN	H <sub>2</sub> O, CO, CO <sub>2</sub> , H <sub>2</sub> , O <sub>3</sub>	1006	1	196	188	114	< 400		
IGP3000 G* SC M	H <sub>i</sub> O <sub>1</sub> CO <sub>2</sub> CO <sub>2</sub> H <sub>2</sub> O <sub>3</sub>	3000	1	234	122	102	< 700		
IGPS000-G1-3C-MIN	H <sub>2</sub> O, CO, CO <sub>2</sub> , H <sub>2</sub> , O <sub>3</sub>	5000	- 1	276	195	186	< 2000		

Model			- Dual Column (DE) Maximum Pressure Drop				
IGP200-G*-DC-M	H <sub>i</sub> O	200	.1	206	156	66	< 700
IGP1000-G1-DC-M	H,O	1006	1	206	230	114	< 900
1GP3000-G* DC:M	цо	3000	1	234	254	102	<1300
/GP5000-GNDC-M	H/O	9000	1	276	292	Title	×.2700
IGP200-G*DC-MN	H <sub>2</sub> O, CO, CO <sub>2</sub> , H <sub>2</sub> , O <sub>3</sub>	200	1	206	158	66	< 700
IGP1000 G* DC MN	H <sub>2</sub> O, CO, CO <sub>2</sub> , H <sub>2</sub> , O <sub>2</sub>	1008	1	206	230	318	< 900
IGR3000-GNDC-M	H <sub>1</sub> O, CO, CO <sub>2</sub> , H <sub>3</sub> , O <sub>3</sub>	3000	- X	284	294	102	s. 1300
IGP5000-G1-DC-MN	H <sub>2</sub> O, CO, CO <sub>2</sub> , H <sub>2</sub> , O <sub>3</sub>	5000	1	276	292	186	< 2700

In-line at the tool to larger flow (pre purification), no power needed



# Heated Getter pou

#### **GASPURI SERIES**

Heated Getter Purifier





Process Gas	Model	Purification			Imp	urities Remo	ved			Lifetime	Flowrates
Process das	Wiodei	Process	O <sub>2</sub>	H <sub>2</sub> O	СО	CO <sub>2</sub>	H <sub>2</sub>	CH <sub>4</sub>	N <sub>2</sub>	Lifetiffe	
Rare Gas	GP-G Series	Getter	<1 ppb	<1 ppb	<1 ppb	<1 ppb	<1 ppb	<1 ppb	<1 ppb	Limited Lifetime	Up to 150 slpm
Nitrogen	GP-G Series	Getter	<1 ppb	<1 ppb	<1 ppb	<1 ppb	<1 ppb	<1 ppb		Limited Lifetime	Up to 150 slpm
Hydrogen	GP-G Series	Getter	<1 ppb	<1 ppb	<1 ppb	<1 ppb			<1 ppb	Limited Lifetime	Up to 100 slpm



#### **GPSERIES** Bulk Gas Purifier (Getter and catalytic)

		Pui	rification	Process					In	purities F	lemoved						
Process Gas	Model	Absor ber	Getter	Catalyst	H <sub>2</sub> O							Acids	Base	Organics	Refractory Compound	Lifetime	Flowrates
Rare Gas	GP-G Series				<1 ppb	<1 ppb	<1 ppb					Limited Lifetime	Up to 300Nm³/hr				
Oxygen	GP-CA Series				<1 ppb	<1 ppb	<1 ppb		<1 ppb	<1 ppb						Auto-Regenerable	Up to 500Nm <sup>3</sup> /hr
Hydrogen	GP-AG Series				<1 ppb	<1 ppb	<1 ppb	<1 ppb		<1 ppb	<1 ppb					Getter has a Limited Lifetime	Up to 100Nm <sup>3</sup> /hr
Hydrogen	GP-A Series				<1 ppb	<1 ppb	<1 ppb	<1 ppb								Auto-Regenerable	Up to 300Nm³/hr
Hydrogen	GP-G Series				<1 ppb	<1 ppb	<1 ppb	<1 ppb		<1 ppb	<1 ppb					Limited Lifetime	Up to 300Nm <sup>3</sup> /hr
Nitrogen	GP-A Series				<1 ppb	<1 ppb	<1 ppb	<1 ppb	<1 ppb							Auto-Regenerable	Up to 20,000Nm <sup>3</sup> /hr
Nitrogen	GP-CA Series				<1 ppb	<1 ppb						Auto-Regenerable	Up to 3,000Nm <sup>3</sup> hr				
CDA	GP-A Series				<1 ppb							<5 ppt	<5 ppt	<5 ppt	<5 ppt	Auto-Regenerable	Up to 300Nm³/hr
CO2	GP-A Series				<1 ppb							<3 ppt	<5 ppt	<5 ppt	<5 ppt	Auto-Regenerable	Up to 700Nm³/hr



### Large purifiers: Getters, Catalytic, PdO

#### **GPSERIES** Bulk Gas Purifier (Getter and catalytic)

Impurity	Standard inlet
CH4	< 25.0 ppm
СО	< 0.5 ppm
CO2	< 2.0 ppm
H2	< 1.0 ppm
H2O	< 3.0 ppm

#### O2 purifier 30Nm3/Hr

- Dual catalytic absorption technology: Technology: Absorber (molecular sieve) + Catalyst (Palladium)
- Conversion of HC, CO and H2 in CO2 and H2O.
   Then removal with molecular sieves
- Dual absorber technology: alternance between purification and regeneration mode
- Absorber regeneratioion via O2 backflush

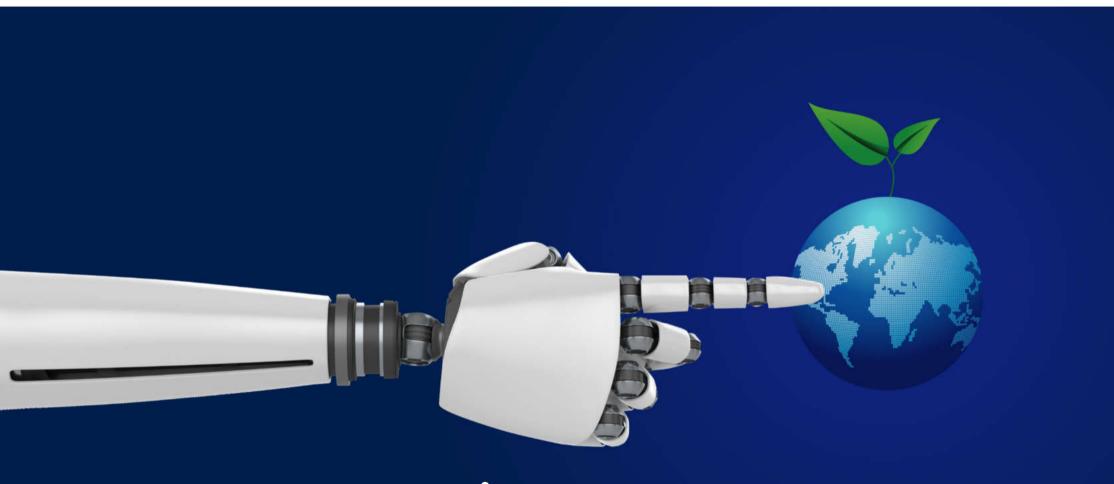


100 Nm3/hr O2 purifier for DB Hitek, second largest foundry in Korea after Samsung

O2 purifiers main specs and required inlet gas purity



Bulkpurifiers



# **Toxic Gases Abatement Systems**



### Toxic Gases Abatement Systems

EXHAUST GAS ABATEMENT PRODUCTS FOR PFCs REMOVAL

- •CLEANSORB dry bed removal of process waste gas.
- •CLEAN-PROTECT safeguard against emergency gas release.
- •CLEANVENT mini cartridge for gas cabinet vent lines.





#### **CLEAN SORB-FABLINE:**

is the standard model for the removal of noxious gas such as Fluorinated compounds, Trichlorosilane, etc. at the production level. It is available in three sizes and can be optimally adapted to the requirements of a pilot line. In addition, it can be adapted to a complete production plant.

#### Applications:

- Plasma Etching: In dry plasma etching, highly reactive radical ions, generated as a low-pressure plasma from halogen gases, are used to etch fine structures into a substrate wafer.
- CVD: Chemical Vapor Deposition is an application used in semiconductor manufacturing to deposit a thin film on the surface of a wafer by means of gaseous compounds.
- ALD: Atomic Layer Deposition (ALD) allows the growth of epitaxial and CVD films to be controlled at the atomic level.
- Ion Implantation
- CIGS Photovoltaic: CIGS Photovoltaics refers to thin films grown from the elements Copper Indium Gallium Seleni de



# Toxic Gasses Abatement Systems

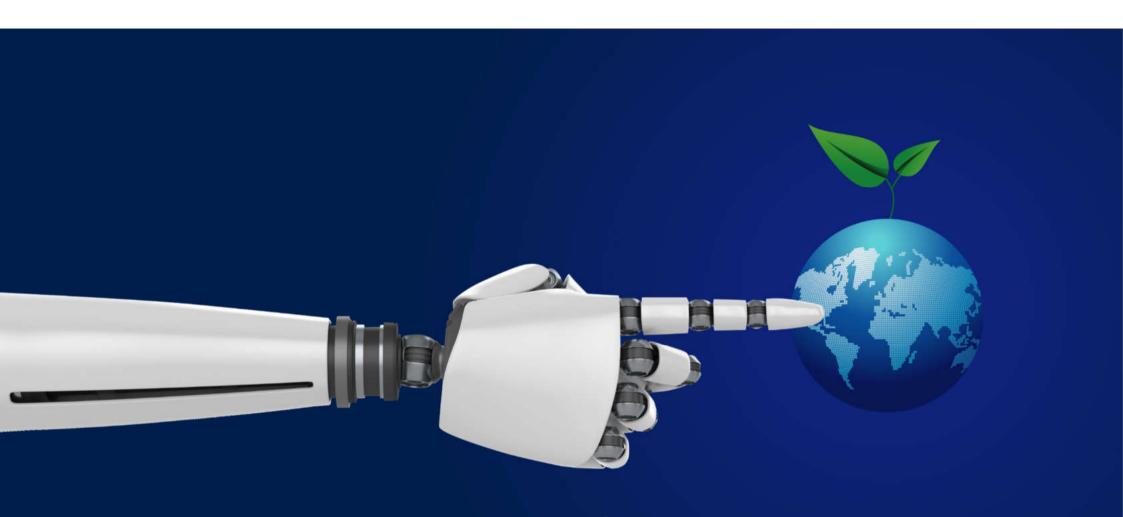
#### **CLEAN VENT:**

Is the safe solution for the removal of hazardous purge gases.

- At-source removal of hazardous vent gases from within gas cabinet or valve manifold box
- •Safe, irreversible conversion of gases to solid by-products at room temperature
- •Cartridges available for over 100 different gases and organometallic precursors







# FM approved Corrosive Fumes Duct Systems



# Corrosive FumesDucting & Fittings

- ETFE COATED STAINLESS STEEL EXHAUST SYSTEMS
- FM APPROVED
  - Research Corporation clean room materials flammability test class 4910
  - Factory Mutual (FM) Research Corporation Standard 4922







# Corrosive FumesDucting & Fittings

#### **ACESIAN DUCTING & FITTINGS:**

Made in Stainless Steel 304 or 316. it ensures that the users can withstand against any damage from water leaks, impact damage and aggressive chemical spills; or even in an event of fire, our ducts & fittings would not burn, melt or collapse. Coating material is ETFE (Ethylene Tetrafluoroethylene).

ETFE is a tough and abrasion resistant material that is virtually unaffected by all industrial chemicals. It is also resistant to alkalis, halogens, inorganic compounds and strong inorganic acids. With approval from Factory Mutual, ACESIAN's ducts are the most corrosive exhaust fume system for use in smoke vapor systems without sprinklers.







Straight Duct



Reducer



90 ° Gore Elbow 45° Gore Elbo



45° Tee







Gas Detection Management



Analyzers Preventive Maintenance



On site Analytical Services



Predictive maintenance

# Services

The multidisciplinary maintenance is provided by professionals with all skills and specializations necessary for the maintenance of high-tech industrial plants in order to ensure continuous production.

#### We guarantee:

- timely intervention and ZERO DOWNTIME
- Just in time management of spare parts and accurate reporting

